

ABSTRACT OF THE DISCLOSURE

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A charged-particle beam drawing data creation method of supplying bit information created from design pattern data in the scanning direction of a

5 charged-particle beam, ON/OFF-controlling the charged-particle beam to irradiate a sample surface, and exposing a two-dimensional pattern by scanning the charged-particle beam includes the step of extracting a cell pattern as one unit of a periodic structure from

10 design pattern data having a periodic structure, and registering the cell pattern, the step of creating arrangement data to be rearranged in a basic drawing region defined by a charged-particle beam exposure apparatus using the cell pattern, and registering the

15 arrangement data, and the step of cutting out data from the cell pattern in accordance with information of the arrangement data, and creating data of the basic drawing region.